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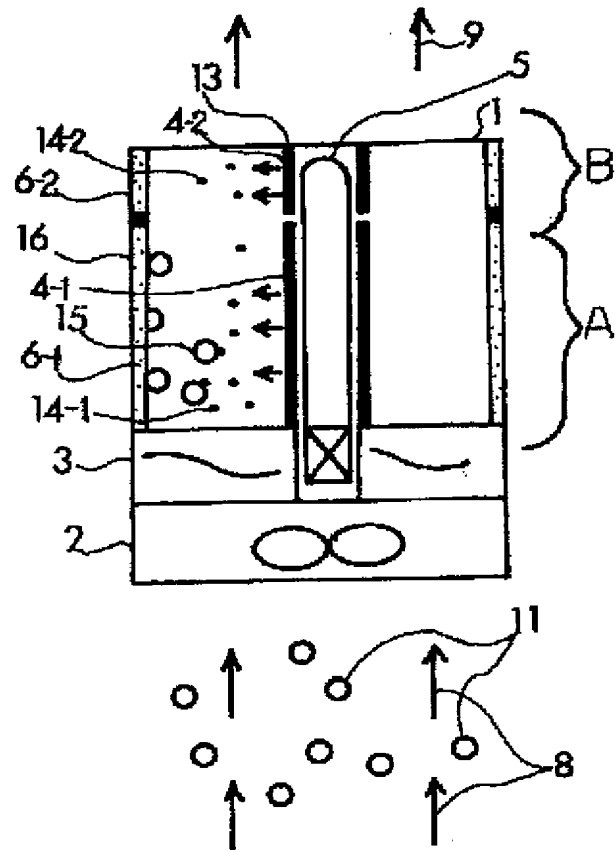
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TITLE : GENERATING METHOD OF NEGATIVE
ION AND DEVICE THEREFOR



ABSTRACT : PROBLEM TO BE SOLVED: To provide a negative ion generating method and the device capable of effectively generating pure negative ion in outside space.

SOLUTION: In the negative ion generating method 1 having a photoelectron emitting material 14, an electrode 6 for electric field and an irradiation source 5 for irradiating the photoelectron emitting material with ultraviolet ray and/or radial ray in the space, the photoelectron emitting material 4 and the electrode 6 for electric field are composed of two parts forming different electric fields of the electric fields 4-1, 6-1 for purifying by the removal of the particles and the electric fields 4-2, 6-2 for negative ion generating and a photocatalyst and/or an adsorbent to purify the negative ion generating gas can be installed in the space.

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